

Title (en)

METHOD FOR CMP OF LOW DIELECTRIC CONSTANT POLYMER LAYERS

Title (de)

VERFAHREN FÜR CMP VON NIEDERDIELEKTRIZITÄTSKOEFFIZIENTEN POLYMERSCHICHTEN

Title (fr)

PROCEDE DE POLISSAGE CHIMIQUE-MECANIQUE DE COUCHES POLYMERES CONSTANTES FAIBLEMENT DIELECTRIQUES

Publication

**EP 1171906 A1 20020116 (EN)**

Application

**EP 00913478 A 20000216**

Priority

- US 0003893 W 20000216
- US 12056799 P 19990218

Abstract (en)

[origin: WO0049647A1] A method for chemical-mechanical polishing of a low dielectric constant polymeric layer wherein a slurry comprising high purity fine metal oxide particles uniformly dispersed in a stable aqueous medium is used.

IPC 1-7

**H01L 21/302**

IPC 8 full level

**C09G 1/02** (2006.01); **H01L 21/3105** (2006.01); **H01L 21/321** (2006.01)

CPC (source: EP KR)

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Citation (search report)

See references of WO 0049647A1

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